

3/26/04

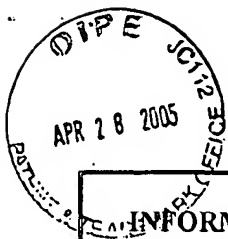
SHEET 1 OF 1

<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811449 Not Yet Assigned			
		APPLICANT Jim Dunphy, et al.					
		FILING DATE Herewith		GROUP Not Yet Assigned			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
Dle	U.S. Pub App No. 2003/0002019	1/2/03	Miller				
	U.S. Pub App No. 2002/0056898	5/16/02	Lopes, et al.				
	U.S. Pub App No. 2002/0063322	5/30/02	Robbins, et al.				
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Dle	5,512,374	4/30/96	Wallace, et al.				
<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
Dle	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247						
	Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13						
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	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3						
	"Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE 0-7803-298-5-6, pgs 91-98						
	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269						
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	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353						
	"Measurement of Micromoto Dynamics in Lubricating Fluids" Deng IEEE						
Dle	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147						
EXAMINER			DATE CONSIDERED 6/2/05				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>INFORMATION DISCLOSURE CITATION</b> APR 28 2005 PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449			
		APPLICANT Dunphy, et al.					
		FILING DATE 3/26/04		GROUP Not Yet Assigned			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
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	6,204,085	3/20/01	Strumpell, et al.				
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	6,259,551	7/10/01	Jacobs				
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DL	2004/0125346	7/1/04	Huibers				
<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
DL	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICKION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKION COATINGS FOR MEMS, Pgs 1-6.						
DL	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKION AND SUPERIOR WEAR RESISTANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.						
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.						
DL	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICKION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.						
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.						
DL	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICKION REDUCTION, 1997 IEEE, Pgs. 1399-1402.						
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<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>  <b>SHEET 2 OF 2</b>			ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449		
			APPLICANT Dunphy, et al.				
			FILING DATE 3/26/04		GROUP Not Yet Assigned		
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
Dle	2004/0012838	1/22/04	Huibers	f	f		
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	6,046,840	4/4/00	Huibers				
	6,844,959	1/18/05	Huibers, et al.				
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Dle	5,287,096	2/15/94	Thompson, et al.				
<b>FOREIGN PATENT DOCUMENTS</b>							
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<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	f						
EXAMINER	Dle			DATE CONSIDERED			6/02/05

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